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**AMENDMENT TRANSMITTAL LETTER (Large Entity)**

Applicant(s): Yoshirou Tsurugida

Docket No.

OKI.291

Serial No.

10/034,379

Filing Date

01/03/2002

Examiner

David Nhu

Group Art Unit

2818

Invention: **METHOD FOR SELECTIVELY OXIDIZING A SILICON WAFER**

MAR 24 2004  
PATENT & TRADEMARK OFFICE

TO THE COMMISSIONER FOR PATENTS:

Transmitted herewith is an amendment in the above-identified application.

The fee has been calculated and is transmitted as shown below.

**CLAIMS AS AMENDED**

	CLAIMS REMAINING AFTER AMENDMENT	HIGHEST # PREV. PAID FOR	NUMBER EXTRA CLAIMS PRESENT	RATE	ADDITIONAL FEE
TOTAL CLAIMS	6 -	20 =	0 x	\$18.00	\$0.00
INDEP. CLAIMS	1 -	3 =	0 x	\$86.00	\$0.00
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					\$0.00
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT					\$0.00

- ☒ No additional fee is required for amendment.
- ☐ Please charge Deposit Account No. \_\_\_\_\_ in the amount of \_\_\_\_\_
- ☐ A check in the amount of \_\_\_\_\_ to cover the filing fee is enclosed.
- ☒ The Director is hereby authorized to charge payment of the following fees associated with this communication or credit any overpayment to Deposit Account No. **50-0238**
- ☐ Any additional filing fees required under 37 C.F.R. 1.16.
- ☐ Any patent application processing fees under 37 CFR 1.17.

  
Signature

Dated: **MARCH 24, 2004**

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I certify that this document and fee is being deposited on \_\_\_\_\_ with the U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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CC:



Serial No. 10/034,379  
OKI.291  
Amendment dated March 24, 2004

*IN THE UNITED STATES PATENT AND TRADEMARK OFFICE*

In re Patent application of :  
Yoshirou Tsurugida : Group Art Unit 2818  
Serial No. 10/034,379 : Examiner David Nhu  
Filed January 3, 2002 :  
METHOD FOR SELECTIVELY OXIDIZING A SILICON WAFER

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**AMENDMENT**

U.S. Patent and Trademark Office  
2011 South Clark Place  
Customer Window, **Mail Stop Non-Fee Amendment**  
Crystal Plaza Two, Lobby, Room 1B03  
Arlington, VA 22202

In response to the Office action of January 9, 2004, please amend the  
above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims which  
begins on page 2 of this paper.

**Remarks/Arguments** begin on page 6 of this paper.